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	Filing Date		2005-05-13	
	First Named Inventor	Shunpu Li		
	Art Unit	4111		
	Examiner Name	Brown		
Attorney Docket Number		05-372		

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1	Kahp Y. Suh et al., "Capillary Force Lithography: Large-Area Patterning, Self-Organization, and Anisotropy Wetting," Adv. Funct. Mater., vol. 12, no. 6+7, pp. 405-413 (June 2002)	<input type="checkbox"/>
2	Stephen Y. Chou et al., "Sub-10 nm imprint lithography and applications," J. Vac. Sci. Technol. B, vol. 15, no. 6, pp. 2897-2904 (Nov/Dec 1997)	<input type="checkbox"/>

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